

00862.022172

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
: Examiner: K. Nguyen  
Yasuhiro SHIMADA et al. )  
: Group Art Unit: 2881  
Application No.: 09/819,669 )  
:   
Filed: March 29, 2001 )  
:   
For: ELECTRON OPTICAL SYSTEM ARRAY, )  
METHOD OF FABRICATING THE SAME, )  
CHARGED PARTICLE BEAM EXPOSURE )  
APPARATUS, AND DEVICE )  
MANUFACTURING METHOD ) June 10, 2003

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

RECEIVED  
JUN 12 2003  
TECHNOLOGY CENTER 2800

REQUEST FOR APPROVAL OF DRAWING CHANGE

Sir:

With the Examiner's approval, and at such time as a Notice of Allowance may issue, Applicants propose to amend the drawing in the above-identified application as follows:

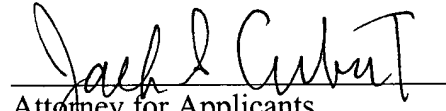
In Fig. 12, change the reference numeral "11a" at the lower left portion of the figure to "11b" as shown therein.

In Fig. 13, insert a reference numeral "23a" as shown therein.

The proposed changes are indicated marked in red on the enclosed duplicate copy of the pertinent figures as filed.

Applicants' attorney, Scott D. Malpede, may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,

A handwritten signature in dark ink, appearing to read "Jack S. Cubert", written over a horizontal line.

Attorney for Applicants

Jack S. Cubert

Registration No. 24,245

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